



PTO/SB/08a/b (08-03)

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use as many sheets as necessary)				Complete if Known	
				Application Number	10/798,822
				Filing Date	March 11, 2004
				First Named Inventor	Cyganski, David
				Art Unit	Not Yet Assigned 1756
				Examiner Name	Not Yet Assigned Caleen O. Sullivan
Sheet	1	of	3	Attorney Docket Number	WP9-001

U.S. PATENT DOCUMENTS					
Examiner Initials*	Cite No. ¹	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number-Kind Code ² (if known)			
/CS/	A1	4,734,746	03-29-1998	Ushida, <i>et al.</i>	
/CS/	A2	5,814,414	09-29-1998	Georger, <i>et al.</i>	
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/CS/	A5	6,586,329	07-01-2003	Tanaka, <i>et al.</i>	
/CS/	A6	6,656,816	12-02-2003	Tomioka	
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FOREIGN PATENT DOCUMENTS						
Examiner Initials*	Cite No. ¹	Foreign Patent Document	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T ⁶
		Country Code ³ -Number ⁴ -Kind Code ⁵ (if known)				
/CS/	A11	JP 7150078	06-13-1995	Sekisui Chem Co Ltd		
/CS/	A12	WO 00/49080	08-24-2000	Chen Yaohong (CA), <i>et al.</i>		
/CS/	A13	WO 01/31401	05-03-2001	Najafi S Iraj (CA), <i>et al.</i>		
/CS/	A14	WO 02/40602	05-23-2002	CIBA Specialty Chemical Holdings, Inc.		
/CS/	A15	WO 02/19407	03-07-2002	Boukherroub, R., <i>et al.</i>		
/CS/	A16	WO 02/079691	10-10-2002	Kuebler, S.M., <i>et al.</i>		
/CS/	A17	WO 02/091433	11-14-2002	Infineon Technologies AG		

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Sheet	2	of	3	Attorney Docket Number	WP9-001

NON PATENT LITERATURE DOCUMENTS			
Examiner Initials	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
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/CS/	B2	Boto, A.N., et al., "Quantum Interferometric Optical Lithography: Exploiting Entanglement to Beat the Diffraction Limit." <i>Physical Review Letters</i> . 2000 Sep; 85(13):2733-36.	
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/CS/	B4	Gannon, T., et al., "Two-Laser-Sensitized Decomposition of Carbon Tetrachloride Photoacid Generation." <i>J. Org. Chem.</i> 1993; 58:5639-42.	
/CS/	B5	Jacobson, J., et al., "Photonic de Broglie Waves." <i>Physical Review Letters</i> . 1995 Jun; 74(24):4835-38.	
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/CS/	B8	Nagasko, E.M., et al., "Nonclassical two-photon interferometry and lithography with high-gain parametric amplifiers." <i>Physical Review A</i> , 2001; 64:043802-1-043802-5.	
/CS/	B9	Pittman, T.B., et al., "Two-photon geometric optics." <i>Physical Review A</i> . 1996 Apr; 53(4):2804-15.	
/CS/	B10	Scaiano, J.C., et al., "Two-Laser, Two-Color Photochemistry from Upper Triplet States of 2-Bromonaphthalene and 9-Bromophenanthrene in Benzene." <i>J. Phys. Chem.</i> 1994; 98:5431-34.	
/CS/	B11	Smith, G.A., et al., "Two-Laser Photochemistry of Phenothiazine in Solution: Ionization and Bond Cleavage from Upper States." <i>J. Phys. Chem.</i> 1994; 98:2923-29.	
/CS/	B12	Steuernagel, O., "Scheme for fourfold de Broglie wavelength reduction of a multi-photon wavepacket." <i>J. Opt. B: Quantum Semiclass. Opt.</i> 4. 2002; S397-S400.	
/CS/	B13	Stekalov, D.V., et al., "Two-Photon Interferometry for High-Resolution Imaging." <i>J. Mod. Optic.</i> 2002; 49:519-27.	
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/CS/	B15	Wang, I., et al., "Three-dimensional microfabrication by two-photon-initiated polymerization with a low-cost microlaser." <i>Optics Letters</i> . 2002 Aug; 27(15):1348-50.	
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/CS/	B17	Wu, P.W., et al., "Two-photon exposure of photographic film." <i>J. Opt. Soc. Am. B</i> . 1999 Apr; 16(4):605-8.	

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¹Applicant's unique citation designation number (optional). ²Applicant is to place a check mark here if English language Translation is attached.

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/CS/	C1	Yablonovitch, E., <i>et al.</i> , "Optical projection lithography at half the Rayleigh resolution limit by two-photon exposure." <i>Opt. Eng.</i> 1999 Feb; 38(2):334-38.	
/CS/	C2	Zhang, B., <i>et al.</i> , "Photochemistry of 1,2-Dibromoethyl." <i>J. Phys. Chem.</i> 1994; 98:7022-28.	

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Sheet	1	of	1
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Complete if Known

Application Number	10/798,822-Conf. #5042
Filing Date	March 11, 2004
First Named Inventor	David CYGANSKI
Art Unit	2020 1756
Examiner Name	Not Yet Assigned Caleen O. Sullivan
Attorney Docket Number	WP9-001

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/CS/	1	US-6,879,376	04-12-2005	Case et al.	

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